



INFORMATION DISCLOSURE STATEMENT	Atty. Docket No.: 150.01110101	Serial No.: 10/632,357
	Applicants: Uhlenbrock et al.	Confirmation No.: 4965
	Filing Date: December 21, 2001	Group: 2812
Information Disclosure Statement mailed: July <u>19</u> , 2002		

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
MG	4,992,137	02/12/91	Cathey, Jr. et al.			
MG	5,254,217	10/19/93	Maniar et al.			
MG	5,380,401	01/10/95	Jones et al.			
MG	5,392,189	02/21/95	Fazan et al.			
MG	5,575,885	11/19/96	Hirabayashi et al.			
MG	5,692,950	12/02/97	Rutherford et al.			
MG	5,711,851	01/27/98	Blalock et al.			
MG	5,786,259	07/28/98	Kang			
MG	5,888,906	03/30/99	Sandhu et al.			
MG	5,916,855	06/29/99	Avanzino et al.			
MG	5,954,997	09/21/99	Kaufman et al.			
MG	5,976,928	11/02/99	Kirlin et al.			
MG	5,981,454	11/09/99	Small			
MG	5,989,988	11/23/99	Iinuma et al.			
MG	6,039,633	03/21/00	Chopra			
MG	6,045,716	04/04/00	Walsh et al.			
MG	6,071,816	06/06/00	Watts et al.			
MG	6,143,191	11/07/00	Baum et al.			
MG	6,149,828	11/21/00	Vaartstra			
MG	6,211,034	04/03/01	Visokay et al.			
MG	6,290,736 B1	09/18/01	Evans			
MG	6,346,741 B1	02/12/02	Van Buskirk et al.			
MG	6,368,518	04/09/02	Vaartstra			
MG	6,395,194 B1	05/28/02	Russell et al.			

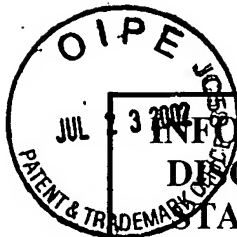
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Maria Guerrero.

Date Considered

4-21-03

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INFORMATION DISCLOSURE STATEMENT	Atty. Docket No.: 150.01110101	Serial No.: 10/032,357
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FOREIGN PATENT DOCUMENTS

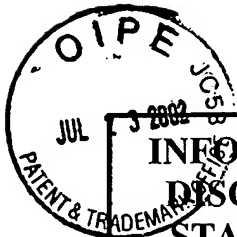
Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
MG	WO 98/06541	02/19/98	PCT				
MG	WO 98/36045	08/20/98	PCT				
MG	WO 99/27581	06/03/99	PCT				
MG	WO 99/53532	10/21/99	PCT				
MG	WO 00/31794	06/02/00	PCT				

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OTHER DOCUMENTS (Including Authors, Title, Date, Pertinent Papers, etc.)

Examiner Initial	Document Description
MG	Canterford et al., "Chapter 9: Rhodium and Iridium," <i>Halides of the Transition Elements, Halides of the Second and Third Row Transition Metals</i> , John Wiley & Sons, New York, NY, 1968; pgs. 346-357, publication page, title page (14 pages total).
MG	DeOrnellas et al., "Challenges for Plasma Etch Integration of Ferroelectric Capacitors in FeRAM's and DRAM's," <i>Integrated Ferroelectrics</i> , 1997;17:395-402.
MG	DeOrnellas et al., "Plasma Etch of Ferroelectric Capacitors in FeRAMs and DRAMs," <i>Semiconductor International</i> , 1997 Sept.; pgs. 103-104, 106 and 108.
MG	Ginzburg et al., <i>Analytical Chemistry of Platinum Metals</i> , John Wiley & Sons, New York, cover pg., and 14-15.
MG	Kim et al., "Chemical Dry Etching of Platinum Using Cl ₂ /CO Gas Mixture," <i>Chem. Mater.</i> , 1998;10:3576-3582.
MG	Kwon et al., "Etching properties of Pt thin films by inductively coupled plasma," <i>J. Vac. Sci. Technol.</i> , 1998;A 16(5):2772-6.
MG	Nakao, "Dissolution of Noble Metals in Halogen-Halide-Polar Organic Solvent Systems," <i>J. Chem. Soc., Chem. Commun.</i> , 1992 March 1; 5:426-7.
MG	Wilberg, <i>Lehrbuch der Anorganischen Chemie</i> , Walter de Gruyter, Berlin, 1985, Cover pg., and 1188.

EXAMINER <i>Yvonne Guerrero</i>	Date Considered <i>4-21-03</i>
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MG	Xu et al., "Chemical Vapor Deposition (CVD) of Iridium and Platinum Films and Gas-Phase Chemical Etching of Iridium Thin Films," <i>Mat. Res. Soc. Symp. Proc.</i> , 1999;541:129-139.

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